

Characterization of dislocations in bulk GaN grown by HVPE

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Photovoltaic properties of GaN around dislocation local





25mV

Structure and stress states



Two peaks appear near the (0004) and (0006) Bragg angles

Compared with stress-free bulk GaN ($c_0 = 5.1850$ Å, $a_0 = 3.1890$ Å), the corresponding lattice constants ($c_1 = 5.1885$ Å, $a_1 = 3.1879$ Å, and $c_2 = 5.1853$ Å, $a_2 = 3.1889$ Å) of the two set peaks indicate that a part of the structure is almost stress-free while the other is compressed.

Self-separation of GaN from sapphire



Stress field applied to dislocation in GaN





	Slip system	cosλ
Basal plane	{0001}<11-20>	0
Prism plane	{1-100}<11-20>	0
	{1-100}<0001>	0
	{11-20}<0001>	0
	{11-20}<1-100>	0
Pryamidal planes	{11-22}<1-100>	0
	{1-101}<11-20>	0
	{1-102}<11-20>	0
	{11-22}<11-23>	0.524
	{1-101}<11-23>	0.454
	{1-102}<1-101>	0.730

Appl. Phys. Lett. 83, 5187 (2003)

$$F_{l} = \frac{Gb^{2}}{4\pi} \frac{1 - v\cos^{2}\alpha}{(1 - v)} \left[\ln\left(\frac{h}{b}\right) + 1 \right] F_{a} = 2Gbh\varepsilon\left(\frac{1 + v}{1 - v}\right) \cos\lambda$$
$$F_{p} = 2Gbh\sec\phi\left(\frac{1 - v\cos^{2}\alpha}{1 - v}\right) \omega \times \exp\left(\frac{-2\pi d(1 - v\cos^{2}\alpha)\omega}{(1 - v)b}\right)$$

$$F_a = F_l + F_p$$
$$F_{net} = F_a - F_l - F_p$$

Misfit dislocation slip in InGaN/GaN heterostructure







J. Huang, K. Xu et al. Appl. Phys. Lett. 98, 221906 (2011)

Dislocation slip during GaN deformation





Cross-section observation by CL and SEM







Dislocation multiplication in GaN





GaN局域塑性变形的各向异性



a面的GaN的阴极荧光图和透射电镜图



在C面的GaN上的塑性变形的位错主要滑移面是{0001}和{10-11}, 而在非极性面GaN上的塑性变形的位错主要滑移面是{0001},从 而导致其弹塑性力学性质的明显差异。

XRD characterization of GaN substrate



CL characterization of GaN substrate



Panchromatic CL image



Panchromatic CL image



Average dislocation density:<1.0X10⁵cm⁻²





Experiment measurement of photovoltaic property around a single dislocation emerged site





Surface recombination rate, experiment and simulated results



